

Atty.
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P-0224.010.US

**INFORMATION DISCLOSURE STATEMENT
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Applicant: GUI et al.

Appln. No.: 10/043,271

Filing Date: January 14, 2002

Date: May 31, 2002

Page 1 of 1

Examiner: UNKNOWN

Group Art Unit: 2851

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P/L	BR 4,952,060	08/1990	INA et al.			
P/L	CR 5,298,988	03/1994	EVERETT et al.			
P/L	DR 5,361,132	11/1994	FARN			
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	HR					
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	JR					
	KR					
	LR					
	MR					
	NR					

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					Enclosed	No	Enclose	No
P/L	OR 0 756 207 A3	01/1997	EUROPE	TANAKA et al.				
	PR							
	QR							
	RR							
	SR							

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

P/L	TR	Patent Abstract of Japan, JP11340120, published December 1999			
P/L	UR	Patent Abstract of Japan, JP05144702, published June 1993			
P/L	VR	Patent Abstract of Japan, JP3246923, published November 1991			
P/L	WR	Patent Abstract of Japan, JP1164032, published June 1989			
P/L	XR	Katagiri et al., "Novel alignment technique for 0.1-μm lithography using the wafer rear surface and canceling tilt effect," <i>Optical Engineering</i> 32(10):2344-2349 (1993)			
P/L	YR	Everett et al., "Aligning lithography on opposite surfaces of a substrate," <i>Applied Optics</i> 31(34):7292-7294 (1992)			
	ZR				
	AAR				

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*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

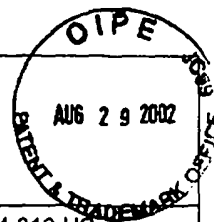
FORM PTO-1449 (modified)
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	SR									

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